IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Dr. Andrey E. Yakshin, et al. Examiner:

Serial No: 10/754,151 Group Art Unit:

Filed: 01/09/04 Date: March 1, 2004

For: **"PROCESSES AND DEVICE FOR THE DEPOSITION OF FILMS ON SUBSTRATES"**

Commissioner for Patents
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING

Sir:

The undersigned hereby certifies that the attached **INFORMATION DISCLOSURE STATEMENT, PTO-1449 FORM, AND 1 REFERENCE** were mailed to the Commissioner for Patents, Alexandria VA 22313-1450, with sufficient first-class postage, no special handling, on **March 1, 2004,** before 5:00 PM, thereby ensuring that such document(s) will be in the hands of the U.S. Postal Service by the close of business this day.

The Commissioner is hereby authorized to charge any fees which might be required or credit any overpayment of fees with regard to the attached document(s) to Account No. **08-3150**.

Respectfully submitted,

HUDAK, SHUNK & FARINE CO. LPA

Daniel J. Hudak, Jr.
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Attorney Docket No.: FMW-BL (CZ 0100)

Enclosures: Return Postcard
Certificate of Mailing
Information Disclosure Statement
PTO-1449 Form
1 Reference

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INFORMATION DISCLOSURE STATEMENT

Sir:

This invention relates to improved current deposition processes and devices for the fabrication of multilayer systems to better control the energy contribution at different stages of the deposition. This is achieved by depositing films by sputtering in a scheme providing for thermalized particles. One can get thermalized particles by choosing the working gas pressure and the distance between target and substrate to result in a mean free path of particles smaller than the distance between target and substrate or to result in a product of pressure and distance being larger than 2,0 cmPa.

Applicant provides the Examiner with the following documents under rule 1.97(b) being filed prior to the first office action. As authorized and encouraged under 37 C.F.R. §1.97-1.99, applicant hereby cites as a means of complying with the duty of disclosure set forth in 37 C.F.R. §1.56, the following patents and/or documents, copies enclosed, which the Examiner should consider with respect to the above-identified United States Patent Application:

ARTICLE
P. J. Martin "Ion-Based Methods for Optical Thin Film Deposition", Journal of Material Science 21 (1986) pp. 1-25 entitled,

Copies of the publications are included for the express purpose of providing the Patent and Trademark Office with an ample opportunity to evaluate the same and to arrive at an independent assessment of their materiality, if any, with regard to the examination of the application.

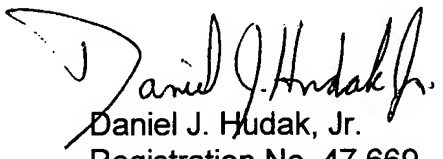
In reviewing the enclosed copies of the above publications, the Examiner is requested to ignore any underscoring or highlighting which may appear because such

markings may or may not have any relationship to the subject matter of the above-identified application. The copies being submitted with this Information Disclosure Statement are the best copies available at this time.

An examination of the present application considering the above documents is requested.

Respectfully submitted,

HUDAK, SHUNK & FARINE CO. LPA



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Attorney Docket No.: FMW-BL (CZ 0100)

Form PTO-1449 U.S. Department of Commerce Patent and Trademark Office **LIST OF PRIOR ART CITED BY APPLICANT** (Use several sheets if necessary)	Atty. Docket No.: FMW-BL	Serial No.: 10/754,151
	Applicant: Dr. Andrey E. Yakshin, et al.	
	Filing Date: 01/09/04	Group:

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing date if appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation Yes No
	AL						
	AM						
	AN						

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	AR		P. J. Martin "Ion-Based Methods for Optical Thin Film Deposition", Journal of Material Science 21 (1986) pp. 1-25 entitled,
	AS		

EXAMINER DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.